

## Reflexion LK 300mm CMP System Operations and Programming

### Who should attend?

This course is designed for those individuals in the semiconductor industry who require basic knowledge of the Reflexion LK 300mm CMP (chemical mechanical planarization) system software.

### Course Benefits

- Provide the software foundation necessary to work effectively with Reflexion LK 300mm CMP systems
- Provide an understanding of system software screens for processing wafers, accessing maintenance screens, and creating recipes and jobs

### Course Objective Summary

- Understand the basic commands required to run wafers on the Reflexion LK system software
- Understand the basic commands required to access maintenance screens on the Reflexion LK system software
- Understand the basic commands required to program jobs and recipes on the Reflexion LK system software

### Course Modules

1. *Basic Operations*
2. *Maintenance Operations*
3. *Programming Operations*

### Registration Information

<b>Prerequisites:</b>	<i>None</i>
<b>Course Length:</b>	<i>3 Hours</i>
<b>Course Type:</b>	<i>Web-Based Training</i>
<b>Course Number:</b>	<i>TRAW1461b</i>

To enroll or for more information on our products and services, please call our registrar at one of the numbers below or go to [www.appliedtraining.com](http://www.appliedtraining.com).

- 1-800-468-8888, option 4 (United States)
- 1-512-272-0027 (International)

### Computer System Requirements:

Attending this course requires a computer using Internet Explorer 5.5 or higher with the plug-in for Flash Player 9. For the audio portion of the class, headsets or speakers are required. 128MB RAM or higher, high-speed Internet access and a screen resolution of 1024 x 768 are also highly recommended.